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Information Disclosure Cover Letter

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PTO Form 1449

Copies of cited Art



PATENT

In The United States Patents and Trademark Office

In the application of:  
**Charles J. Molnar**

Case number: **1FALL112903**

Application no.: **10/724535**

Group art: **3723**

Filed: **11/29/03**

Examiner: **Anthony Ojini**

For: **In situ finishing aid control**

Date: **4-7-04**

Information Disclosure Statement

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Commissioner for Patents  
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Alexandria, VA 22313-1450

Sir:

In compliance with 37 CFR 1.56, 1.97, and 1.98, Applicants bring to the attention of the U. S. Patent and trademark Office information listed in the enclosed PTO-1449. A copy of the information is also enclosed.

Applicant, for convenience of PTO, lists pending and / or published applications for consideration:

Application Number	Filing date	Related publication / patent
09/435,181	11-5-99	6,283,829
09/434,723	11-5-99	6,267,644
09/434,722	11-5-99	6,293,851
09/434,724	11-5-99	
09/435,180	11-5-99	6,204,181 with drawn from issue
09/533,473	3-23-00	6,346,202
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09/954,394	9-17-01	
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10/251,341	9-20-02
10/260,458	9-30-02
10/699,066	9-30-02
10/724,535	11-29-03

Application with serial number 09/435180 has been published with number  
6,204,181 B1.

Very Respectfully Yours,



Charles J. Molnar

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015  
APR 09 2004  
PATENT & TRADEMARK OFFICE  
Form PTO-1449 (modified by applicant)  
Information disclosure citation in an application  
Applicants: Charles J. Molnar/

Dock. #: 1FALL112903  
Applic #: 10/724535  
Filing Date: 12/29/03  
Group art unit: 3723

### US Documents

Exam Initial	Document number	Date	Name	Class	Sub class	Filing date if approp.
	6298470	8-2-2001	Breiner et al.	716	4	
	6293851	9-25-01	Molnar	451	41	
	6291349	9-18-01	Molnar	438	609	
	6283829	9-4-01	Molnar	451	8	
	6268641	7-31-01	Yano et al.	257	260	
	6267644	7-31-01	Molnar	451	41	
	6263255	7-17-01	Tan et al.	700	121	
	6257953 b1	7-10-01	Gittis et al.	451	5	
	6197604 B1	3-6-01	Miller	438	14	
	6121143	9-19-00	Messner et al.	438	692	
	5993298	11-30-99	Duescher	451	56	
	5985045	11-16-99	Kobayashi	148	240	
	5972793	10-26-99	Tseng	438	692	
	5968280	10-19-99	Ronay	134	2	
	5958794	9-28-99	Bruxvoort	438	692	
	5954997	9-21-99	Kaufman	252	79.1	
	5954975	9-21-99	Cadien	216	38	
	5945347	8-31-99	Wright	438	692	
	5934978	8-31-99	Burke	451	A36	
	5919082	7-6-99	Walker	451	41	
	5916855	6-29-99	Avanzino	51	307	
	5910041	6-8-99	Duescher	451	28	
	5906754	5-25-99	Appel	216	88	
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	5885137	3-23-99	Ploessl	106	3	

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	WO 99/64527	12-16-99	Sachan et al.	C09G	1/02	
	WO 98/08919	3-5-98	Kalota et al.	C10M	A2	
	WO 00/00567	1-6-00	Kaufman et al.	C09K	3/14	
	WO 00/00561	1-6-00	Kaufman et al.	C09G	1/02	

### Other documents (including Author, Title, Date, Pertinent pages, etc.)

	6204181 withdrawn from issue, Molnar, filed 11-5-99, published March 20, 2001, serial number 09/438180
	BERMAN, MIKE et al., "Review of in Situ and in Line Detection for CMP Applic.", Semiconductor Fabtech, 8 <sup>th</sup> edition, pp. 267-274.
	BIBBY, THOMAS, "Endpoint Detection for CMP", Journal of Electronic Materials, Vol. 27, #10, 1998, pp. 1073-1081.

Examiner:	Date considered:
Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

Form PTO-1449 (modified by applicant) Information disclosure citation in an application	Dock. #: 1FALL112903	Applic #: 10/724535
Applicants: Charles J. Molnar/	Filing Date: 12/29/03	Group art unit: 3723

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Exam Initial	Document number	Date	Name	Class	Sub class	Filing date if approp.
	5876490	3-2-99	Ronay	106	3	
	5876266	3-1-99	Miller	451	56	
	5860847	1-19-99	Sakurai et al.	451	10	
	5858813	1-12-99	Scherber	438	693	
	5842909	12-1-98	Sandhu	451	7	
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	5749769	5-12-98	Church	451	5	
	5743784	4-28-98	Birang	451	21	
	5740033	4-14-98	Wassick et al.	364	149	
	5738562	4-14-98	Doan	451	5	
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	5722879	3-3-98	Cronin	451	281	
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	5695384	12-9-97	Beratan	451	28	
	5691895	11-25-97	Kurtzberg et al.	364	148	
	5685766	11-11-97	Mattingly	451	36	
	5667629	9-16-97	Pan	438	13	
	5647952	7-15-97	Chen	156	636.1	
	5643060	7-1-97	Sandhu	451	285	
	5639388	6-17-97	Kimura	216	84	
	5614444	3-25-97	Farkas	437	225	
	5609517	3-11-97	Lofaro	451	529	
	5609511	3-11-97	Moriyama	451	5	
	5597442	1-28-97	Chen	156	626.1	
	5595526	1-21-97	Yau	451	8	
	5537325	7-16-96	Iwakiri et al.	364	468.28	
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Other documents (including Author, Title, Date, Pertinent pages, etc.)

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	Filing Date: 12/29/03	Group art unit: 3723
Applicants: Charles J. Molnar		

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Exam Initial	Document number	Date	Name	Class	Sub class	Filing date if approp.
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	5340370	8-23-94	Cadien	51	38	
	5314843	5-24-94	Yu	437	225	
	5308438	5-3-94	Cote	156	636	
	5196353	3-23-93	Sandhu	437	7	
	5166080	11-24-92	Schietinger	437	7	
	5154512	10-13-92	Schietinger	374	9	
	5137544	8-11-92	Medillin	51	308	
	5107445	4-21-92	Jensen	36	525	
	5069002	12-3-91	Sandhu	51	165R	
	4421068	12-20-83	Aral	122	448	

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	“Understanding and Using Cost of Ownership”, Wright Williams & Kelly, Dublin, CA, rev 0595-1
	“Intermetal Dielectric Cost-of-Ownership”, Case, C.B. and Case, C. J., <u>Semiconductor International</u> , June 1995, pp 83-88
	“Using COO to select Nitride PECVD clean cycle”, Anderson, Bob, et al., <u>Semiconductor International</u> , Oct. 1993, pp 86-88
	“The application of cost of ownership simulation to wafer sort and final test”, Jimez, D. W. et al., SEMI’s Manufacturing test Conference, July, 1993
	“Reducing Tungsten Deposition equipment cost of ownership through in situ contamination prevention and reduction”, Burghard, R. W., et al., <u>Microcontamination</u> , Oct. 1992, pp 23-25
	“Reducing ion-implant equipment cost of ownership through in situ contamination prevention and control”, Burghard, R. W., et al., <u>Microcontamination</u> , Sept. 1992, pp 27-30
	“Reducing tungsten-etch equipment cost of ownership through in situ contamination prevention and reduction”, Burghard, R. W., et al., <u>Microcontamination</u> , June 1992, pp 33-36
	“Reducing process equipment cost of ownership through in situ contamination prevention and reduction”, Burghard, R. W., et al., <u>Microcontamination</u> , May. 1992, pp 21-24
	“Cost of ownership for inspection equipment”, Dance D. and Bryson, P., Sematech, Austin, Texas, date unknown

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